

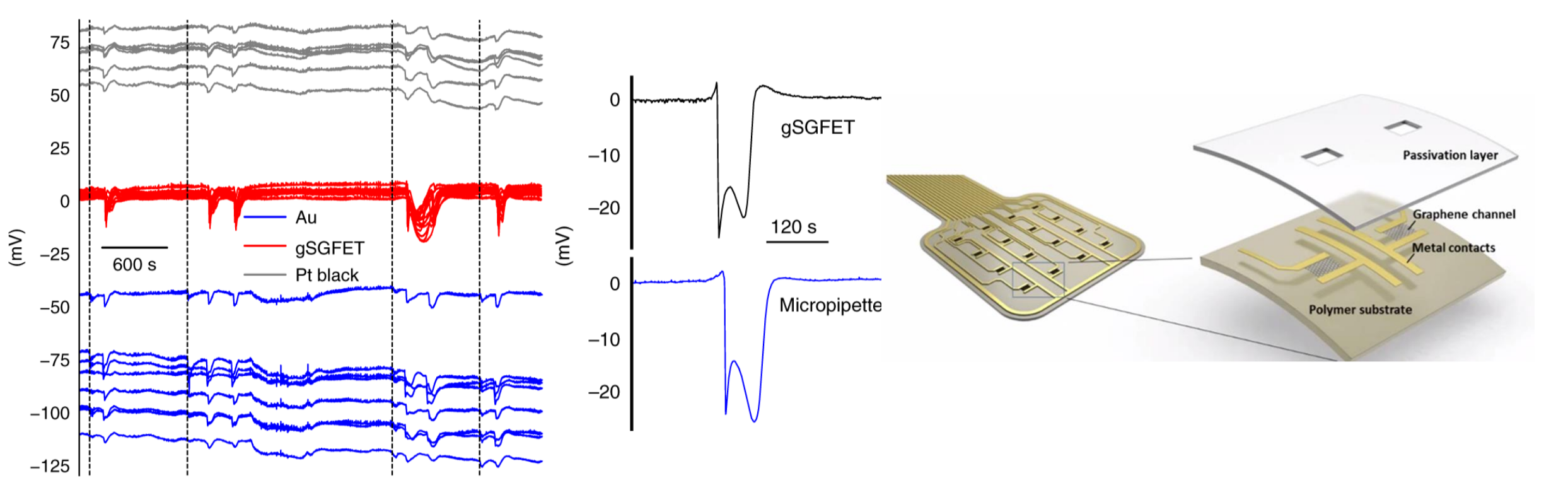
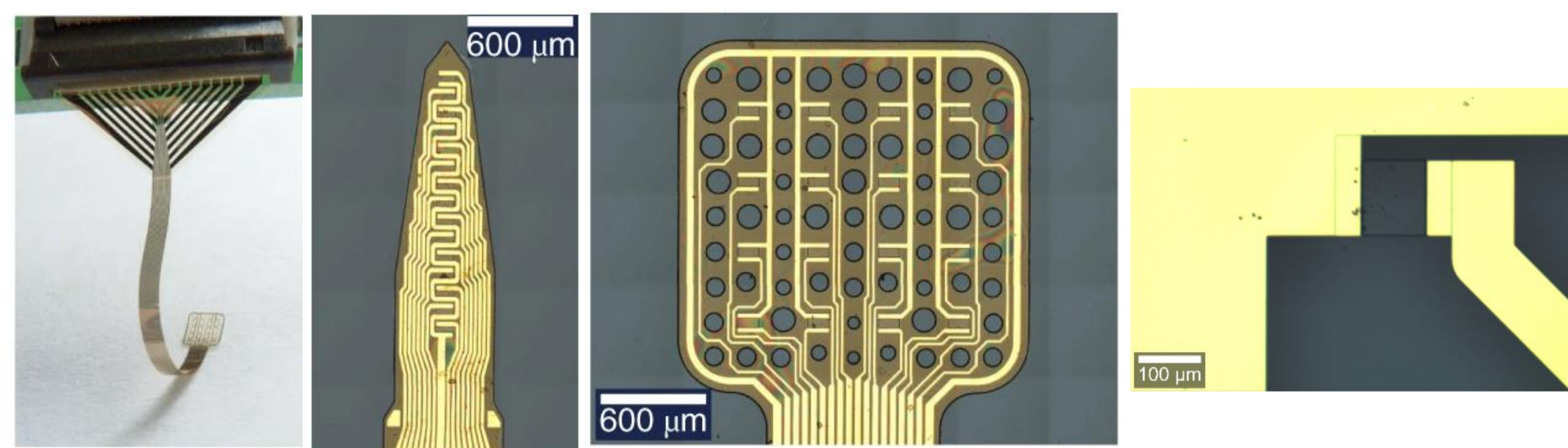
Encapsulation and protection strategies for graphene-based solution-gated field-effect transistors towards high performing neural recording

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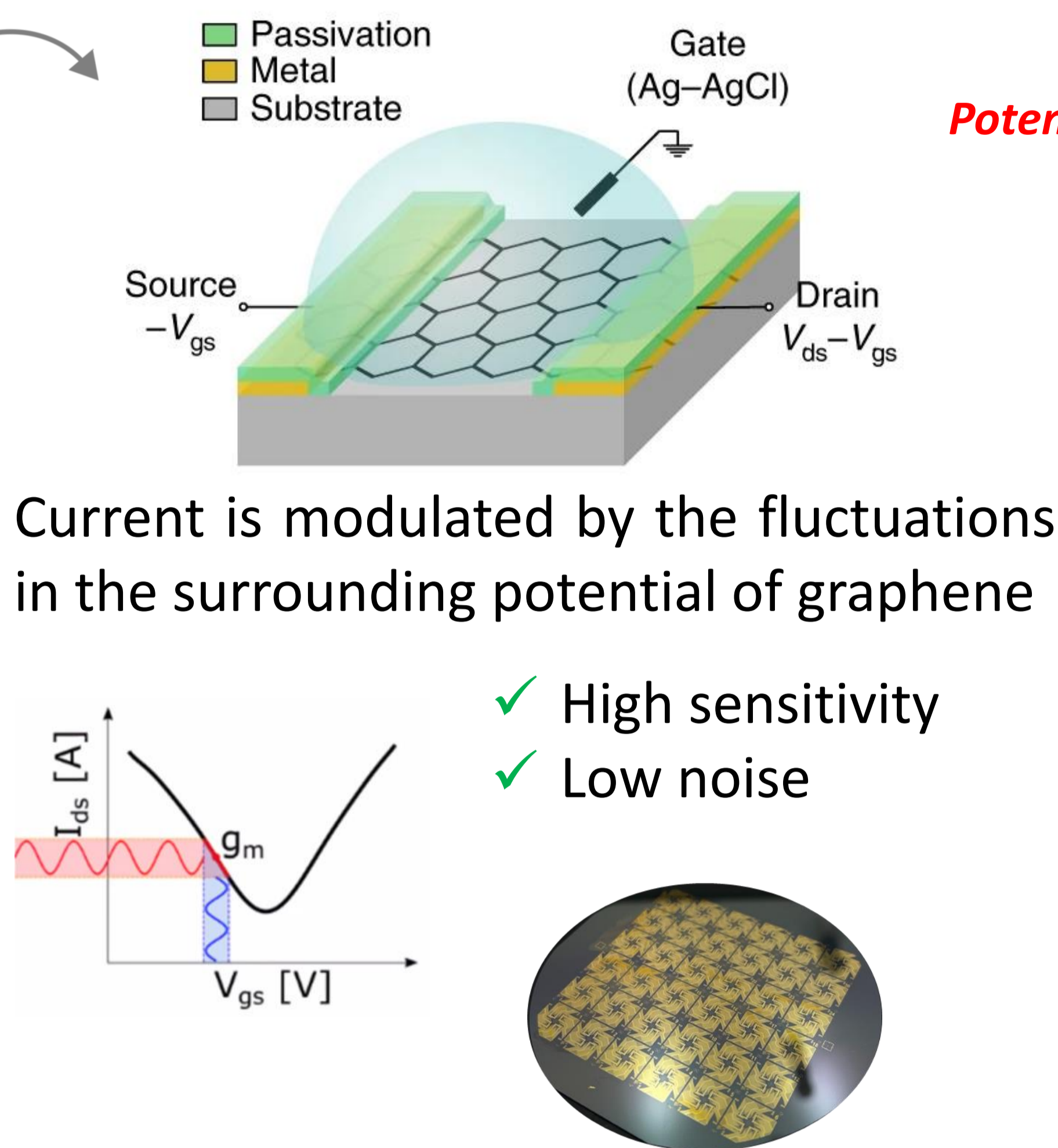
TOWARDS HIGH PERFORMING gSGFETs

High-resolution recording of brain activity



gSGFETs allow the recording of infraslow brain activity (ISA) in a large-scale, implantable, biocompatible clinical system for applications in monitoring and treatment of neurological diseases like epilepsy or stroke [1,2].

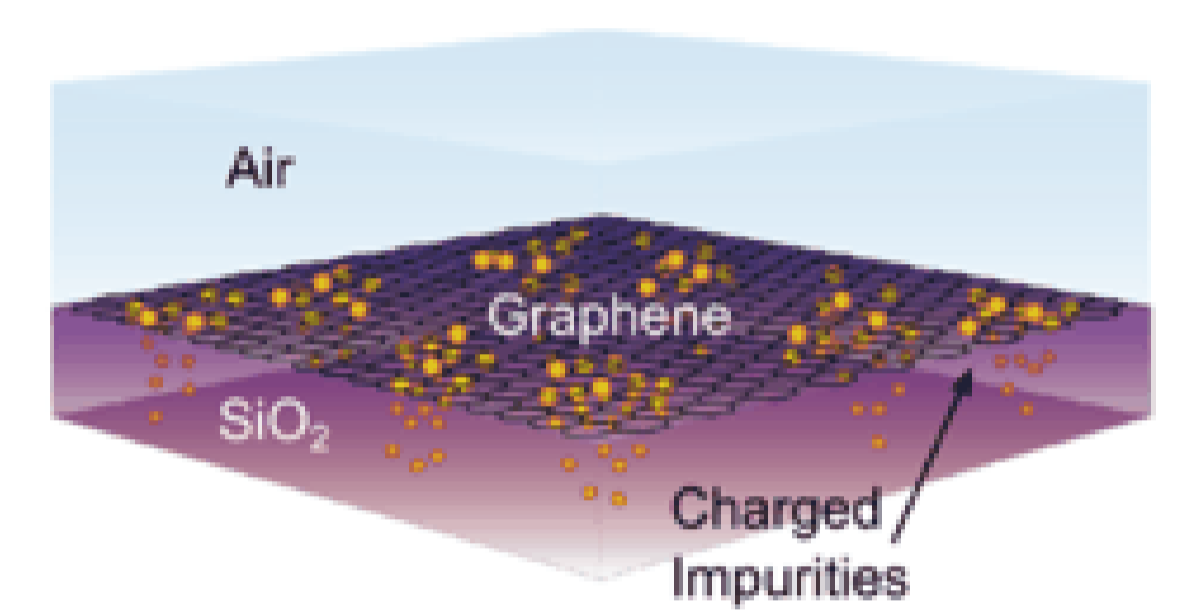
Working principles



Challenges

Potential not fully used!

- ✗ Microfabrication contamination
- ✗ Graphene transfer residues
- ✗ Substrate interaction [3]



✗ Limited electrical performance

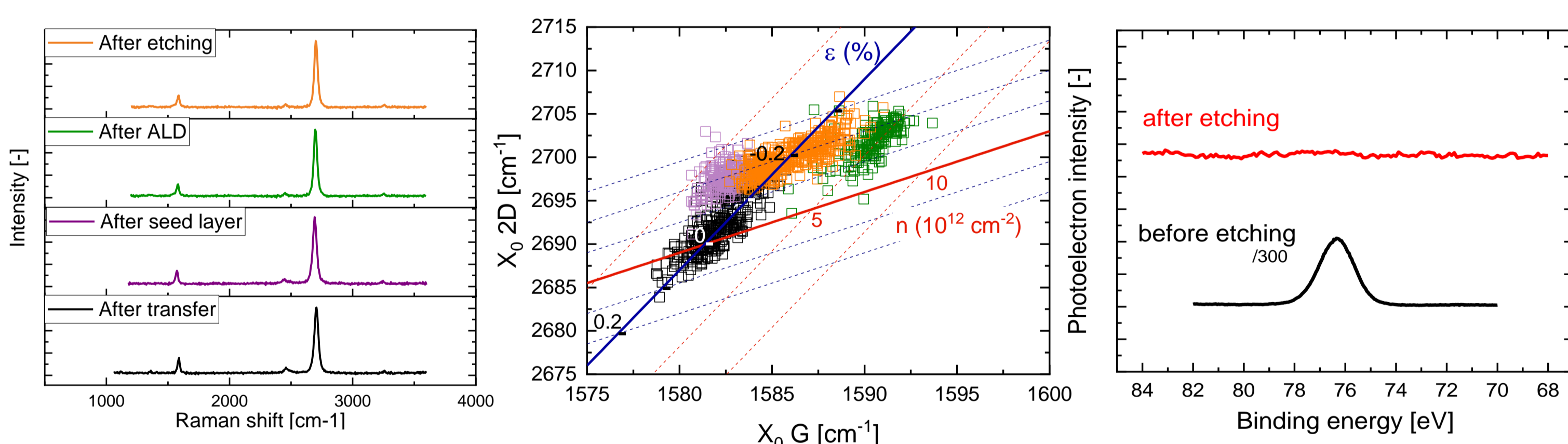
Channel protection with sacrificial layers

Towards enhanced performance and protection against fabrication residues of gSGFETs a fabrication process modification has been proposed:

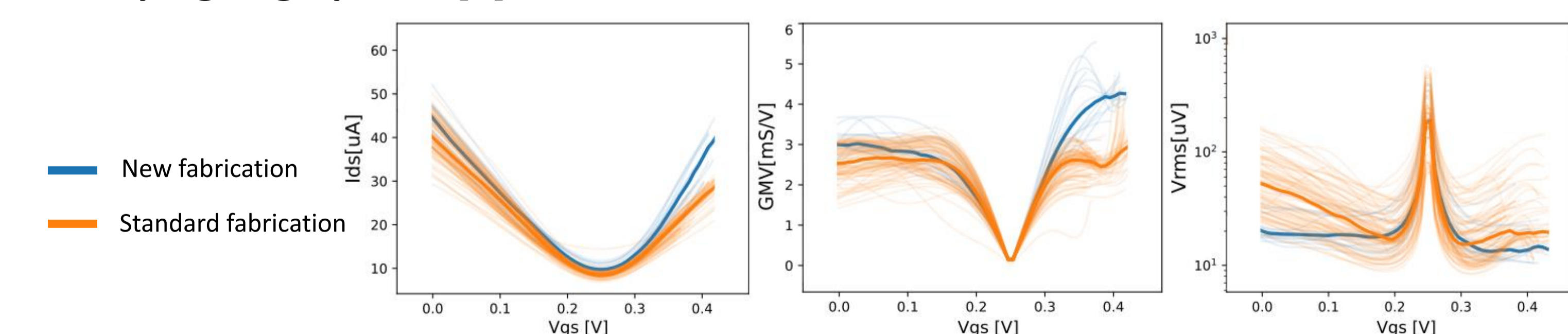
- Metal contacts
- SU8 passivation
- Si/SiO2
- Al+Al2O3



- Low-temperature atomic layer deposition (ALD) of Al₂O₃ with Al seed layer approach after graphene transfer.
- Residue-free removal of the layer at the end of the fabrication process.



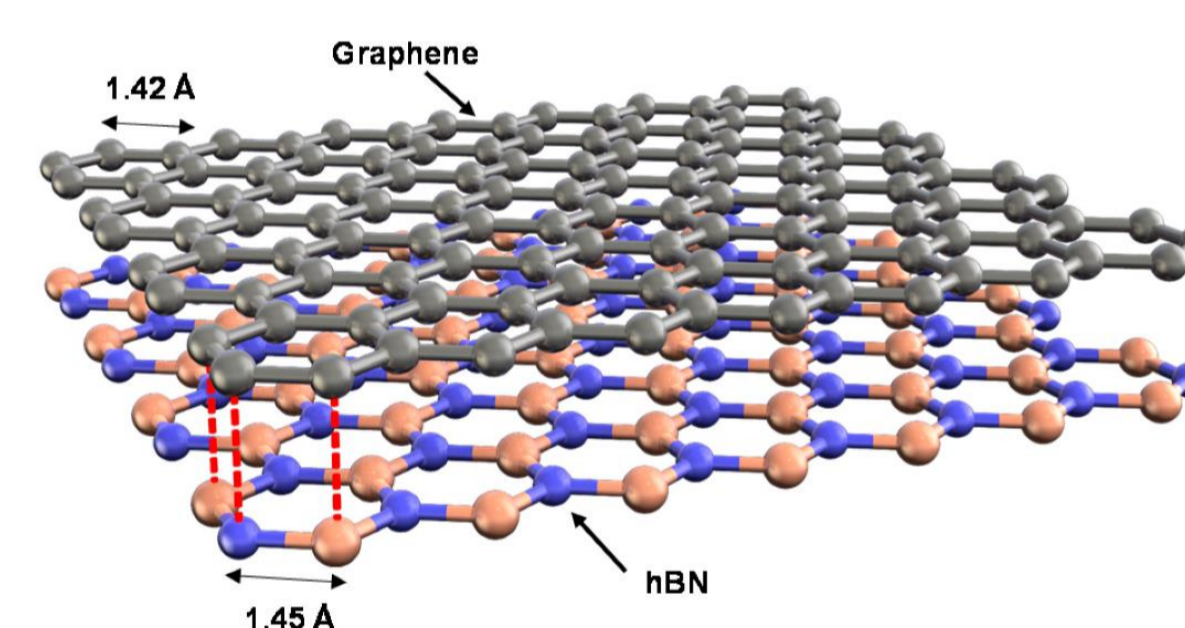
- Al seed layer induces low levels of strain while the ALD layer induces clear n-doping to graphene [4].
- 1M HCl effectively etches Al₂O₃ without damaging graphene (slight strain change).



Al₂O₃ protection demonstrates a potential in improving the electrical performance of gSGFETs and future work will focus on optimizing the fabrication process to confirm it.

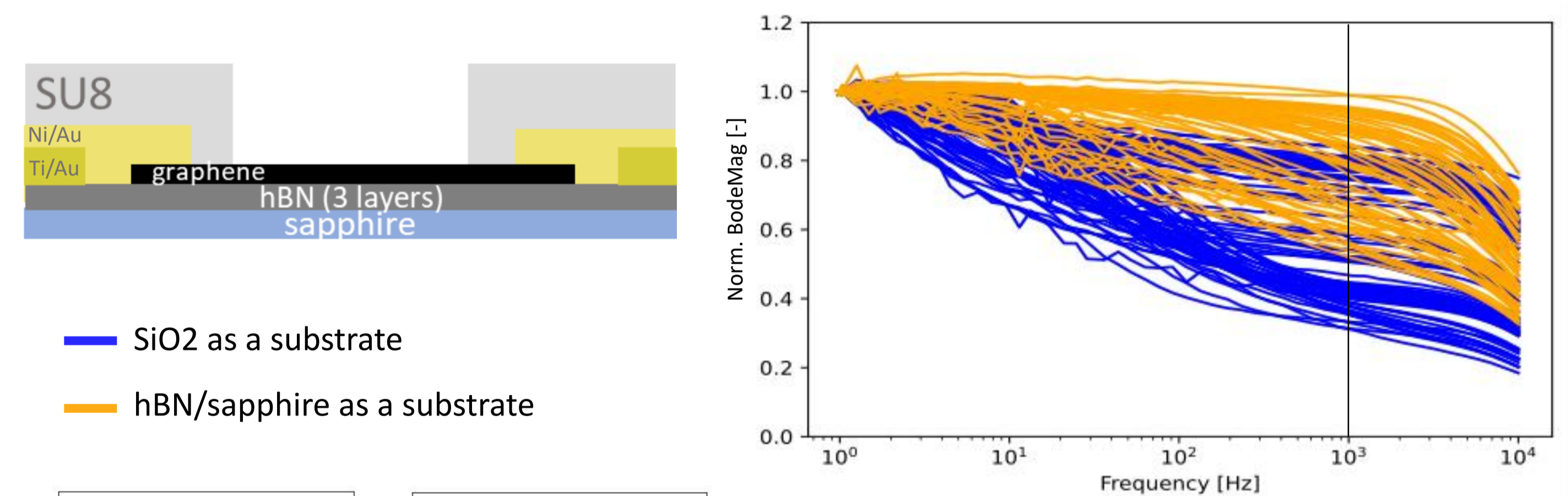
Reducing charge scattering from the substrate

Hexagonal boron nitride (h-BN)



- Reduces substrate interaction
- Reduces charge carrier scattering
- Improves thermal management

- Atomically flat surface (hBN-graphene lattice mismatch: ~1.6%)
- Crystalline structure, wide band gap (5–6 eV)
- High thermal conductivity [4]



Keeping constant frequency response up to tens of kHz important for signal recording

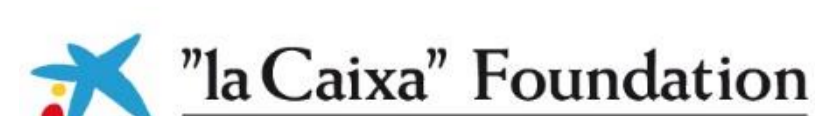
Future work will involve exploring the hBN as a decoupling layer on different substrates (SiO₂, PI), benchmarking the performance, and understanding its influence on graphene-based devices.

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ACKNOWLEDGEMENTS

The ICN2 is funded by the CERCA programme / Generalitat de Catalunya, and supported by the Severo Ochoa Centres of Excellence programme, Grant CEX2021-001214-S, funded by MCIN/AEI/10.13039.501100011033
This project has received funding from the European Union's Horizon Europe research and innovation programme under grant agreement No 101136541 - GphT-BCI
A. Graf acknowledges the support of a fellowship from "La Caixa Foundation" (ID 100010434). The fellowship code is "LCF/BQ/DI22/11940031".



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